

02/08/2011

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants	:	Yasuo KOBAYASHI, et al.	Confirmation No.:	7185
U.S. Serial No.	:	10/549,859		
Filed	:	June 6, 2006		
Examiner	:	Michael G. Miller		
Group Art Unit	:	1792		
For	:	PLASMA-ASSISTED DEPOSITION METHOD AND PLASMA-ASSISTED DEPOSITION SYSTEM		

**AFTER FINAL AMENDMENT RESPONSE UNDER 37 CFR 1.116**

**Mail Stop: AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the Final Office Action of November 1, 2010, to which the time for response is set to expire February 1, 2011, please amend the application as set forth below and consider the following remarks.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.